

- Manual modular wet process station
- Configurable for wet strip and clean applications
- Recirculating filtered process tank option
- Quick dump rinse
- Spin spray dryer or surface tension gradient dryer option
- Manual movement of cassettes to processing tanks
- Auxiliary chemical distribution option
- User-friendly software with touch screen interface
- Aerodynamically designed and tested to optimize airflow

MicroTech Systems is an established wafer and substrate cleaning capital equipment company. The Otter™ Manual Wet Process Station is the platform for multiple stripping and cleaning processes such as sulfuric peroxide [SPM], RCA critical cleaning, dilute HF, and hot phosphoric nitride strip. The Otter is also available for solvent cleaning.

The configurable Otter wet process station enables temperature and concentration controlled processes. This manual system can be custom configured to include multiple temperature-controlled recirculating tanks, quick dump rinse tanks, and a spin dryer or surface tension gradient dryer option.



**MICROTECH
SYSTEMS, INC.**

4466 Enterprise Street, Fremont CA 94538 phone: 510.651.5277 fax: 510.651.3374

Product

Wafer sizes up to 300 mm
Front or rear maintenance access options
Chemical compatible components
Compliant with SEMI standards; S2-93
CE certifications NFPA 79
Factory Mutual (FM) certification
Configurable to customer needs
Chemical distribution system option

Custom tanks for each chemical
Temperature controlled tanks
Megasonics available
Recirculating and filtering available
Quick dump rinse
Spin dryer or surface tension gradient dryer option

User-friendly software interface option



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